

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION: Duck Kyun CHOI

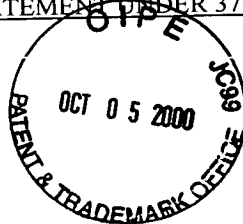
GROUP ART UNIT: 2823

SERIAL NUMBER: 09/170,625

EXAMINER: S. Hawranek

FILED: October 13, 1998

FOR: METHOD FOR FABRICATING A THIN FILM TRANSISTOR

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. 1.97Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Applicant(s) wish to disclose the following information.

REFERENCES

- The Applicant(s) wish to make of record the references listed on the attached Form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.

- A check is attached in the amount required under 37 CFR § 1.17(p).

RELATED CASES

- Attached is a list of applicant's pending applications or issued patents which may be related to the present application. A copy of the patent(s) is attached along with PTO 1449.

- ☐ A check is attached in the amount required under 37 CFR § 1.17(p).

CERTIFICATION

The undersigned certifies that

- ☐ each item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- ☐ no item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR § 1.56(c) more than three months prior to the filing of this statement.

PETITION

- ☐ Applicant(s) hereby request consideration of the attached information. A check is attached in the amount of the Petition fee required under 37 CFR § 1.17(i)(1).

DEPOSIT ACCOUNT

- Please charge any additional fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit account No. 50-0911. A duplicate copy of this sheet is enclosed.

10/06/2000 SSITHIB1 00000030 09170625

01 FC:126

240.00 OP

Date:

October 5, 2000Sixth Floor
701 Pennsylvania Avenue, N.W.
Washington, D.C. 20004
Telephone No: (202) 624-1200
Facsimile No: (202) 624-1298

Respectfully submitted,

LONG, ALDRIDGE & NORMAN LLP

Rebecca A. Goldman
Attorney of Record
Registration No. 41,786RECEIVED
OCT 13 2000
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Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO.: 8733.6836		SERIAL NO.: 09/170,625	
LIST OF REFERENCES CITED BY APPLICANT (Use Several Sheets if Necessary)				APPLICANT: Duck Hyun CHOI			
				FILING DATE: October 13, 1998		GROUP: 2823	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	4,309,225	01/1982	FAN et al.	148	1.5	
	AB	4,626,448	12/1986	HAYS	427	39	
	AC	5,364,664	11/1994	TSUBOUCHI et al.	427	535	
	AD	5,492,843	02/1996	ADACHI et al.	437	21	
	AE	5,576,222	11/1996	ARAI et al.	437	4	
	AF	5,619,044	04/1997	MAKITA et al.	257	64	
	AG	5,639,698	06/1997	YAMAZAKI et al.	437	228	
	AH	5,663,077	09/1997	ADACHI et al.	438	151	
	AI	5,677,240	10/1997	MURIKAMI et al.	437	195	
	AJ	5,985,741	11/1999	YAMAZAKI et al.	438	486	
	AK	6,066,547	05/2000	MAEKAWA	438	486	
	AL						
	AM						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AN	21-40915	05/1990	JP (Japan)	Abstract		
	AO	80-06053	01/1996	JP (Japan)	Abstract		
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)							
	AP	Y. Kawazu, et al., "Low-Temperature Crystallization of Hydrogenated Amorphous Silicon Induced by Nickel Silicide Formation", Japanese Journal of Applied Phys., Vol. 29, No. 12, December 1990, pp. 2698-2704					
	AQ						
	AR						
	AS						
EXAMINER:					DATE CONSIDERED:		

*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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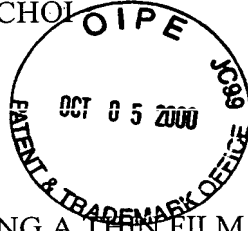
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RELATED CASES STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Applicant hereby provides a list of pending U.S. applications or issued patents which may be related to the present application.

<u>Examiner's Initial</u>	<u>U.S. Serial Number</u>	<u>Filing Date</u>	<u>Inventor Name</u>	<u>Our Ref.</u>
_____	09/115,498	04/14/98	JANG et al.	8733.6584
_____	09/299,571	04/27/99	JANG et al.	8733.8205
_____	09/350,816	04/09/99	JANG et al.	8733.20020


Date Considered: _____

Respectfully submitted,

LONG, ALDRIDGE & NORMAN LLP

October 5, 2000

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